



DEP & REF

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Konstantin Holdermann  
Application No. : 10/090,915  
Filed : March 5, 2002  
Title : ETCHING SOLUTION FOR WET CHEMICAL PYRAMIDAL  
TEXTURE ETCHING OF SILICON SURFACES  
Grp./Div. : 1765  
Examiner : Shamim Ahmed  
Docket No. : 47585/RAG/S969

Confirmation No.7688

REQUEST FOR REFUND

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Post Office Box 7068  
Pasadena, CA 91109-7068  
August 11, 2005

Commissioner:

The Notice of Allowance for the above-identified application was vacated on May 3, 2005, and a new Office action was issued on the same date. Accordingly, Applicant hereby requests a refund of the issue fee in the amount of \$1370.00. In the newly issued Office action, Applicant was advised of its ability to request a refund of the issue fee, which it paid on December 2, 2004.

Applicant hereby requests that the refund amount of \$1370.00 be credited to deposit account 03-1728, show its reference number (S969:47585). A copy of this request is enclosed.

Respectfully submitted,

CHRISTIE, PARKER & HALE, LLP

By 

Robert A. Green  
Reg. No. 28,301  
626/795-9900  
10/18/2005 RECEIVED  
10/18/2005 SDENB02 00000039 10090915  
-1370.00 OP

RAG/ldb  
Enclosure: Copy of this request  
LDB PAS637395.1-\*08/10/05 10:43 AM

I hereby certify that this correspondence is being deposited with the U.S. Postal Service as first class mail in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on 8/11/05

BEST AVAILABLE COPY (Date of Deposit)